

## Supporting Information

### **Ultra-Low Ice Adhesion Enabled by Nano-Engineered Poly (ionic liquid)-Elastomeric Films: Leveraging Aqueous Lubrication and Elasticity**

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## Supporting figures and tables for Results and Discussion

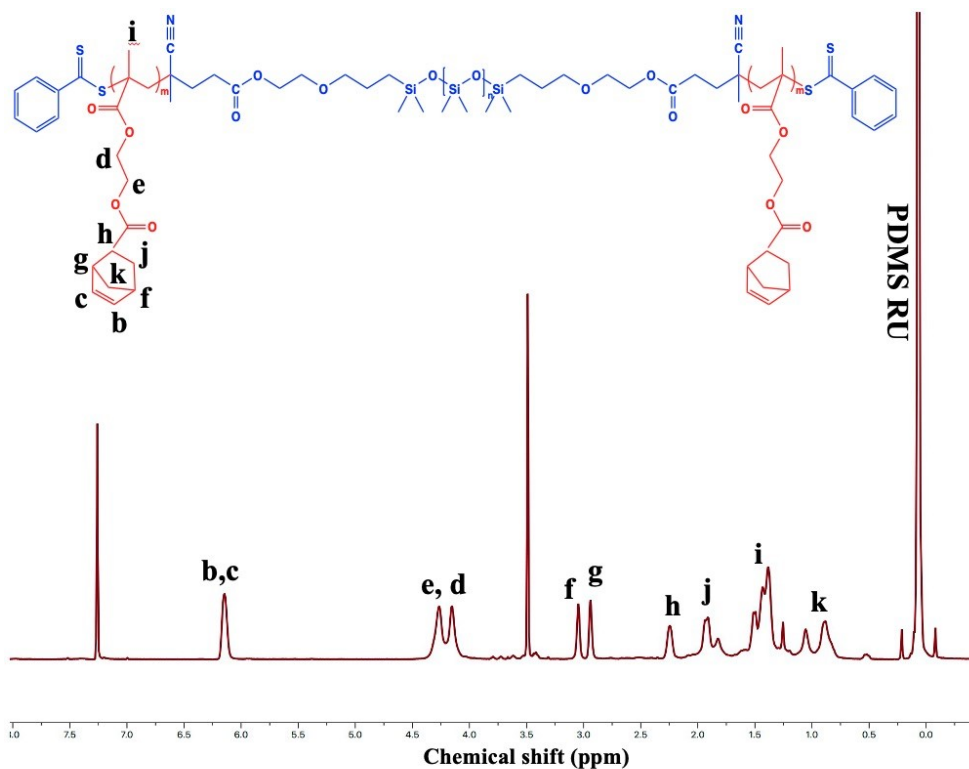


Fig. S1 <sup>1</sup>H NMR spectrum of the triblock copolymer of PDMS-*b*-(PNBMMA)<sub>2</sub> (P10 macrocrosslinker) in CDCl<sub>3</sub>.

Table S1. Composition and molecular weight of the synthesized P5 and P10 macrocrosslinkers.

Designation	Feeding ratio of M: RAFT: I (mol)	DP <sub>n</sub>	M <sub>n</sub> (×10 <sup>4</sup> )		PDI	Conv. (%)
			<sup>1</sup> H NMR	GPC		
P5	5:1:0.2	5	1.42	2.1	2.1	90
P10	10:1:0.2	9	1.54	2.4	1.8	91

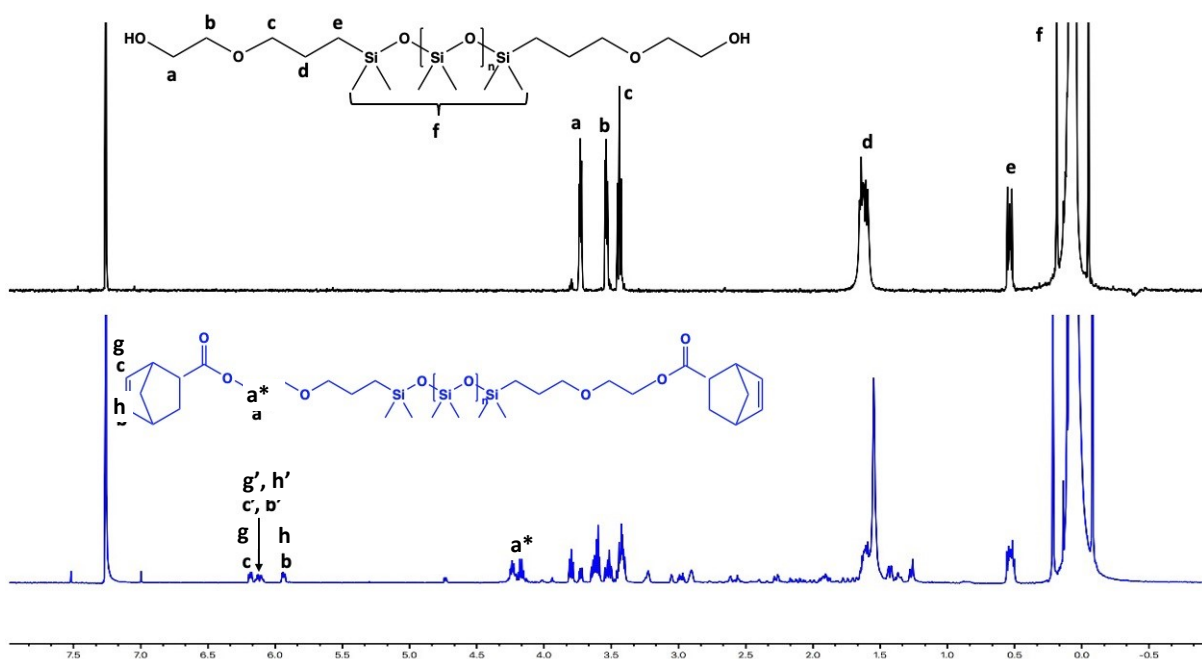
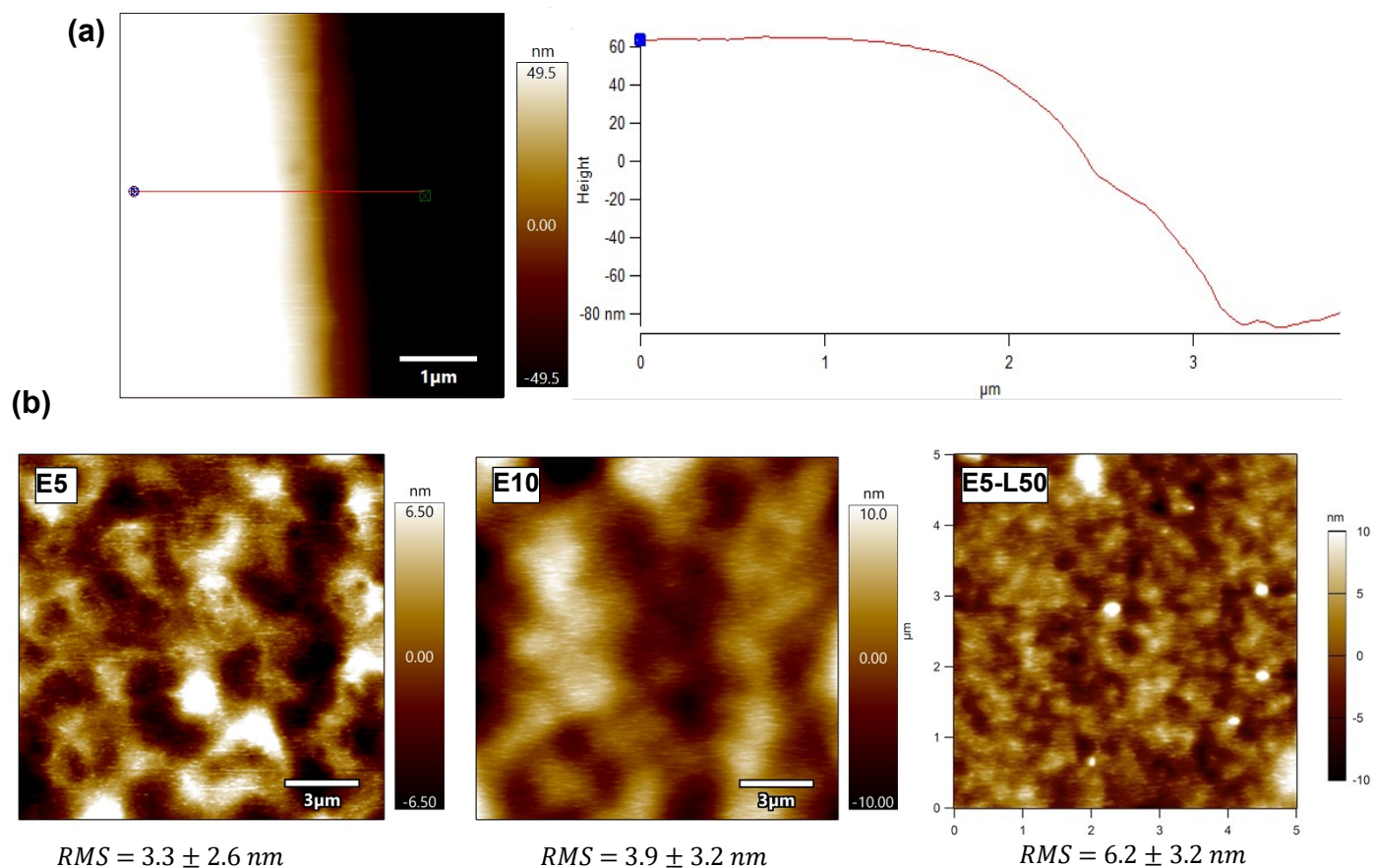
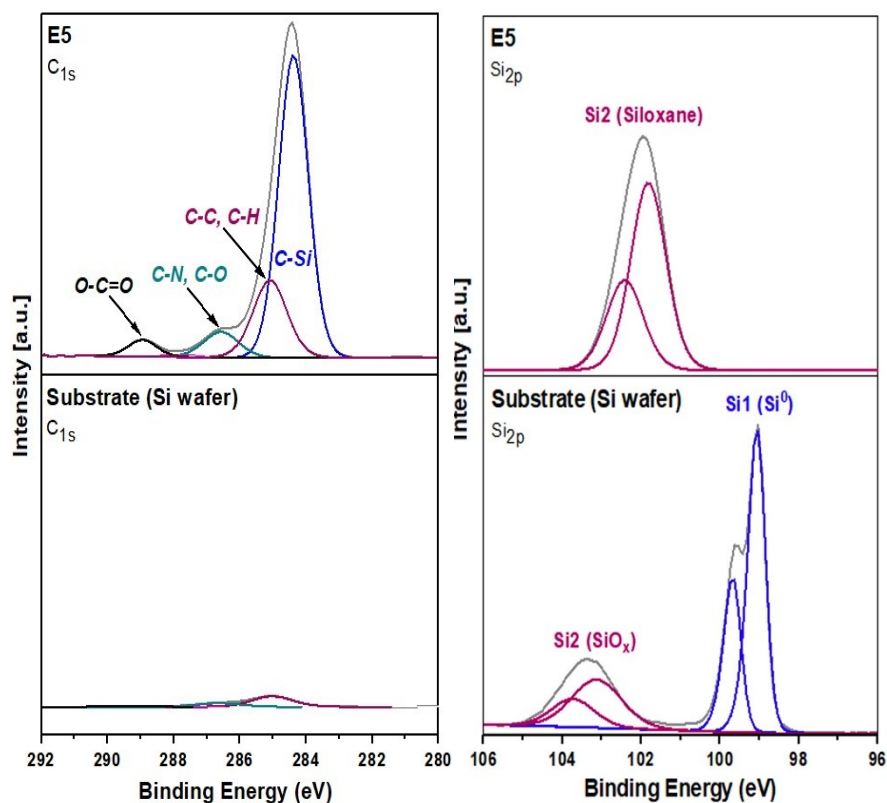


Fig. S2 <sup>1</sup>H NMR spectrum of bis-(hydroxyethoxypropyl) polydimethylsiloxane and norbornene-terminated PDMS macrocrosslinker (NB-PDMS-NB, P2) in CDCl<sub>3</sub>.



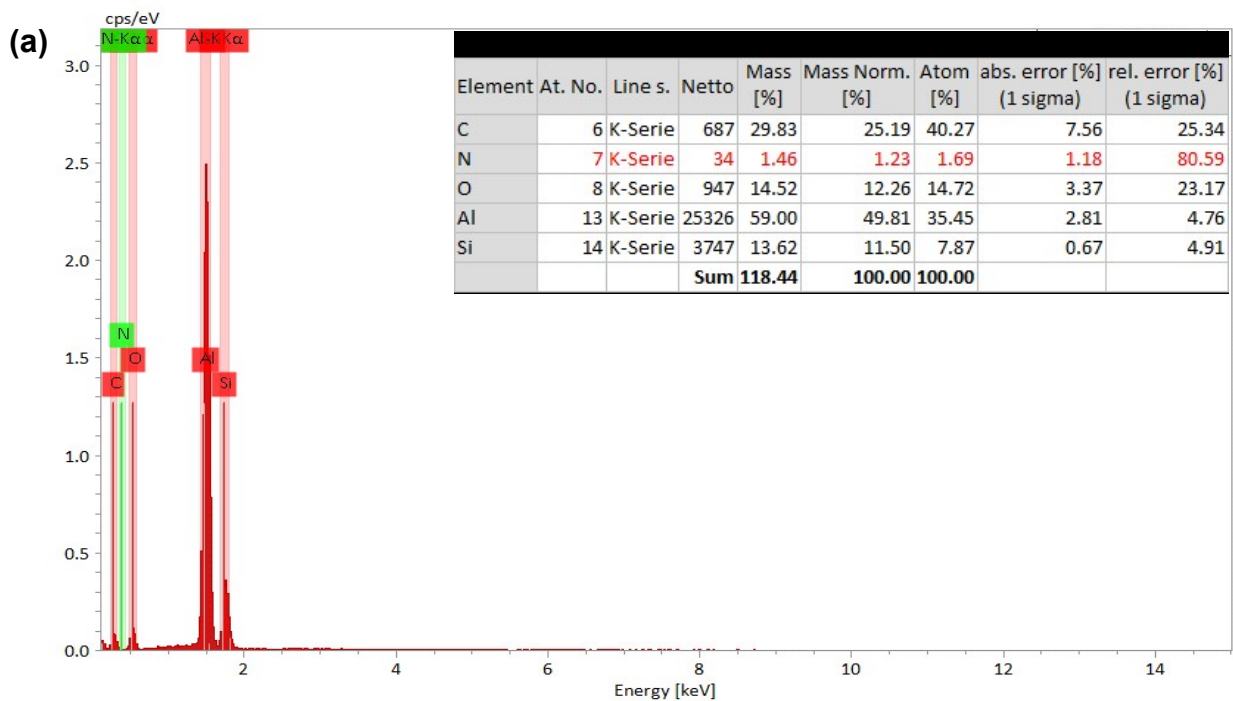
**Fig. S3** (a) Thickness estimation using AFM scratch technique, and (b) AFM height images of elastomers and PIL-infused elastomers.



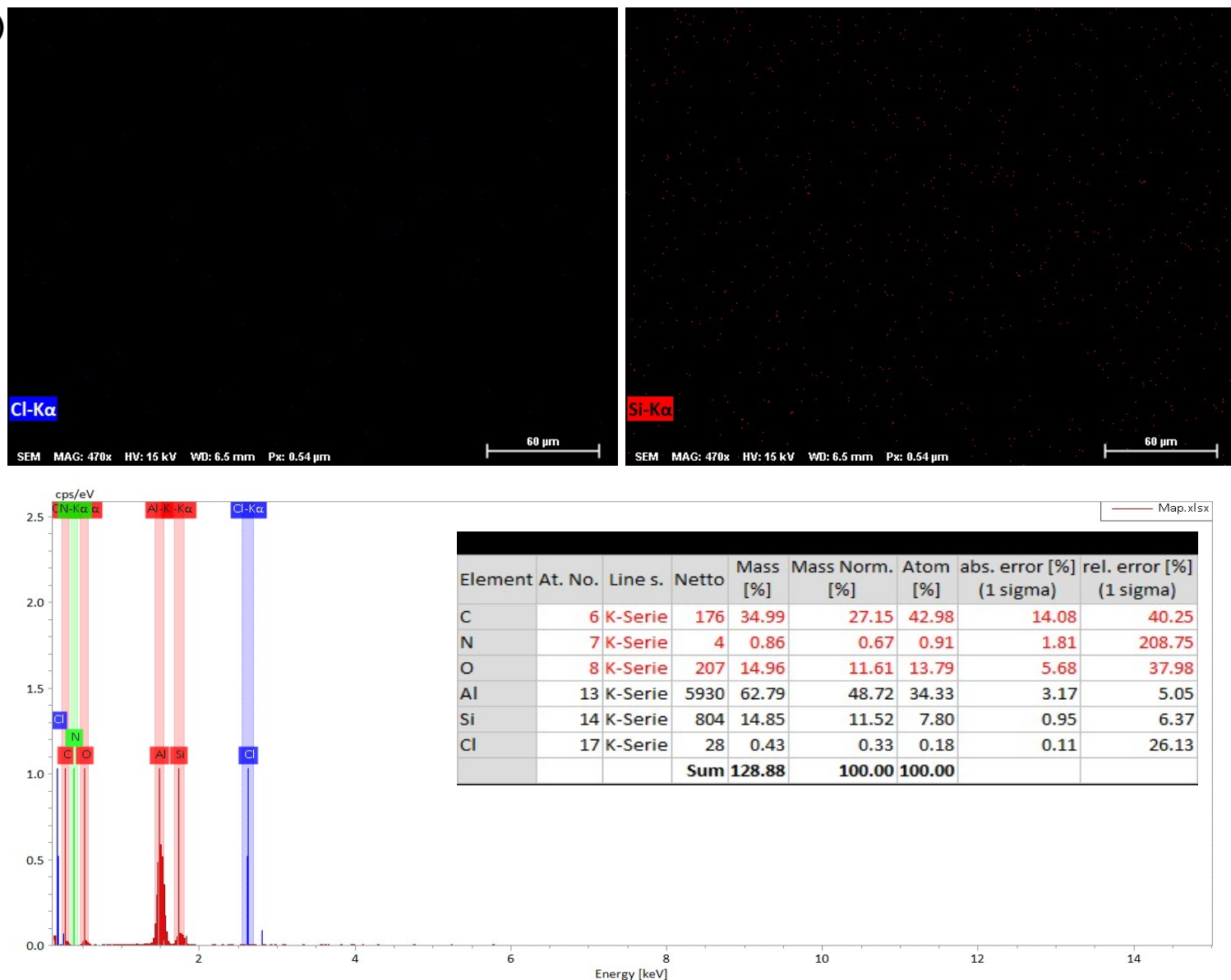
**Fig. S4** X-ray photoelectron spectroscopy (XPS) data (i.e., C<sub>1s</sub> and Si 2p high resolution spectra) of the substrate and surface-tethered E5 elastomer.

**Table S2.** Elemental composition (%) of the substrate and E5 elastomer obtained by ssCAP<sub>ROMP</sub> process determined by X-ray photoelectron. spectroscopy (XPS) analysis.

Atomic %	Substrate (Silicon Wafer)		E5		Assignments
	Mean	std	Mean	Std	
<b>O</b>	38.0	7.1	24.5	0.2	
<b>N (total)</b>	0.1	0.1	0.2	0.0	
N1			0.2	0.0	All organic N other than N <sup>+</sup> , NO <sub>x</sub>
N2			0.0	0.0	N <sup>+</sup>
N3			0.0	0.0	NO <sub>x</sub>
<b>C (total)</b>	5.6	0.2	56.1	0.2	
C1	0.0	0.0	37.4	0.7	C-Si
C2	3.8	0.2	11.9	0.8	C-C, C-H
C3	1.3	0.2	4.0	0.0	C-N, C-O
C4	0.1	0.0	0.5	0.1	C=O, N-C=O
C5	0.4	0.0	2.1	0.1	O-C=O
<b>Si</b>	56.2	7.4	18.7	0.1	
Si1	34.4	8.6	0.1	0.1	Si <sup>0</sup> i.e., Si-Si
Si2	21.8	1.2	18.6	0.0	Siloxane, SiO <sub>x</sub>
<b>Si2/Si1</b>	0.6		289.7		Film thickness/contribution for the E5
<b>Si2/C</b>			0.33		PDMS assignment check in E5



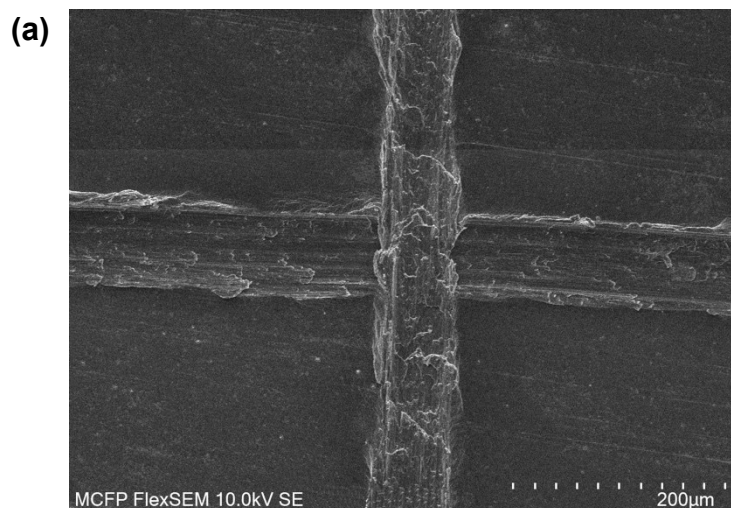
(b)



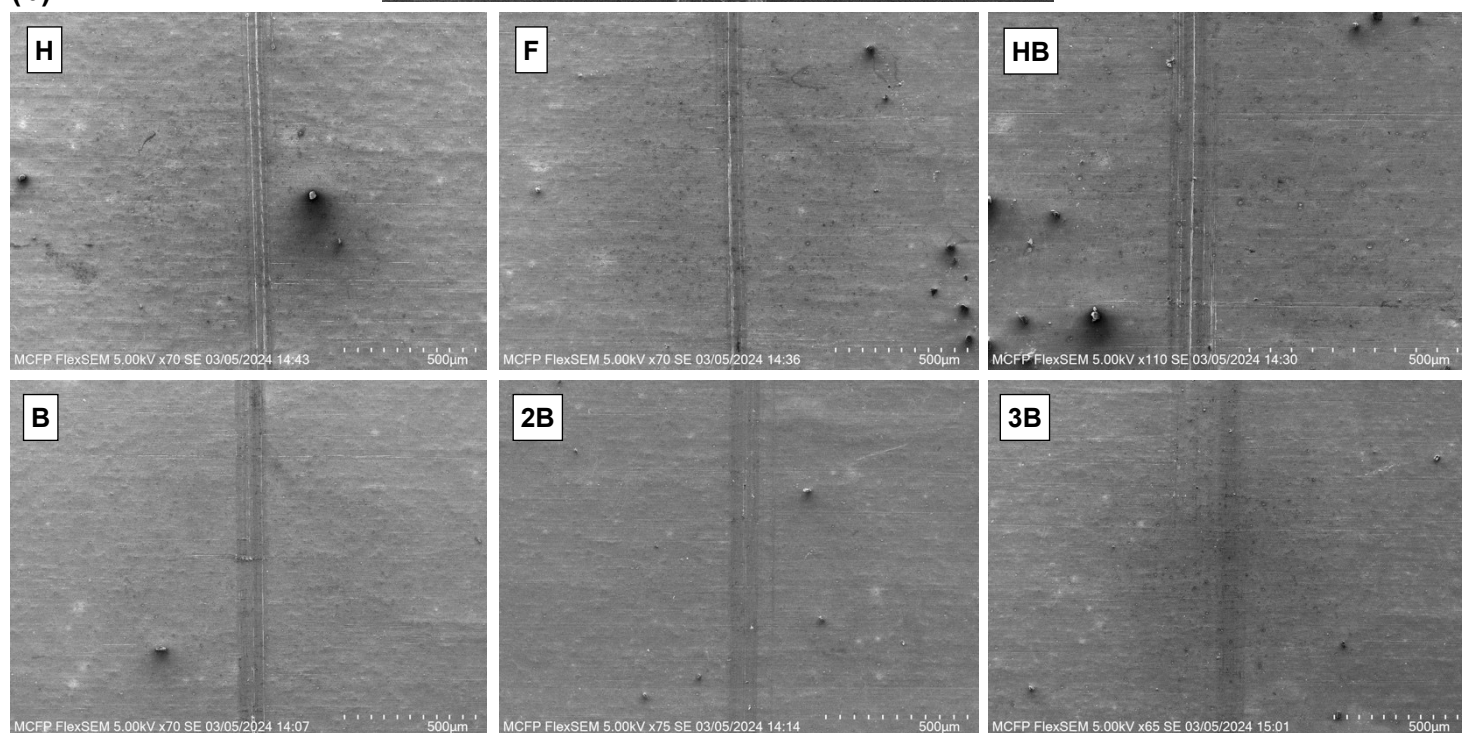
**Fig. S5** Energy Dispersive X-ray (EDX) analysis of the coatings: (a) E2 Elastomeric film, and (b) E2-L20 film demonstrating elemental mapping of silicon and chlorine over the surface of the film.

**Table S3.** Surface wettability results of the fabricated elastomers and E2-L20 PIL-infused elastomer.

Designation	Static CA (°)	Advancing CA (°)	Receding CA (°)	Hysteresis (°)
<b>E10</b>	104.9 ± 2.7	110.3 ± 0.8	63.9 ± 0.7	46.4 ± 3.0
<b>E5</b>	99.6 ± 1.4	106.7 ± 0.5	65.9 ± 2.5	40.8 ± 8.8
<b>E2</b>	105.5 ± 0.5	110.1 ± 0.3	71.7 ± 0.9	38.4 ± 1.4
<b>E2-L20</b>	102.5 ± 3.5	109.5 ± 0.3	85.2 ± 1.7	26.5 ± 15.5



(b)



**Fig. S6** Mechanical durability assessment of the E2-L20 PIL-infused film: (a) FESEM image of the surface after the crosshatch test, and (b) FESEM images of the films subjected to scratching with pencils of different hardness grades (i.e., pencil hardness test). The sequence of hardness ranges from hardest to softest: H, F, HB, B, 2B, 3B.